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PATENT  
Customer No. 22,852  
Attorney Docket No. 07553.0028

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: )  
Ken KOBAYASHI et al. ) Group Art Unit: 1746  
Application No.: 10/069,208 ) Examiner: Not assigned  
Filed: February 22, 2002 )  
For: METHOD OF ETCHING )

Commissioner for Patents  
Washington, DC 20231

Sir:

**PRELIMINARY AMENDMENT**

Prior to the examination of the above application, please amend this application  
as follows:

**IN THE SPECIFICATION:**

Please amend the specification as follows:

Please delete page 17 in its entirety.

**IN THE CLAIMS:**

Please cancel claims 1-5 without prejudice or disclaimer, and add new claims 6-  
15, as follows:

6. (New) A method of etching an organic film on a workpiece, the organic film  
having an etching mask, the method comprising:

placing the workpiece in a hermetically sealed process chamber;